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Applicant(s)

Casimer M. DeCusatis, et al.

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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Bann, R., et al., "Micromachining system accommodates large wafers," Laser Focus World, www.optoelectronics-world.com, pp. 189-192, January 2001

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Kartalopoulos, S., "OTHER OPTICAL COMPONENTS," IEEE, Chapter 9, pp. 131-137, (1999)

Carroll, J., et al., "Distributed feedback semiconductor lasers," IEE Circuits, Devices and Systems Series 10, SPIE Press Monograph, Vol. PM52, pp 9-15, (1998)

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DATE CONSIDERED

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